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Via Express Mail Label #EL540189538US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: TSUTOMU YAMADA, ET AL.

FOR: DEPOSITION MASK AND MANUFACTURING METHOD THEREOF, AND  
ELECTROLUMINESCENCE DISPLAY DEVICE AND MANUFACTURING  
METHOD THEREOF

PRELIMINARY AMENDMENT

Box Patent Application  
The Assistant Commissioner of  
Patents and Trademarks  
Washington, DC 02031

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Date of Deposit December 26, 2000  
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Sir:

Jennifer Matson  
(Typed or printed name of person mailing paper or fee)  
Jennifer Matson  
(Signature of person mailing paper or fee)

Prior to the Examiner acting in the above-referenced application, please preliminary  
amend the abstract and claims as follows:

IN THE ABSTRACT:

Please amend the abstract as follows:

A single crystal or polycrystalline silicon substrate [(100)] is formed as a semiconductor  
substrate. Using a resist [(103)], an SiO<sub>2</sub> film [(101)] is formed as a first coating on at least part  
of the outer periphery of the substrate [(100)]. While using this SiO<sub>2</sub> film [(101)] as a mask, the  
substrate [(100)] is etched from the first surface side using KOH or the like. The thickness of the